

**PATENT APPLICATION**

**RESPONSE UNDER 37 CFR §1.116  
EXPEDITED PROCEDURE  
TECHNOLOGY CENTER ART UNIT 1722**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of

Ryoji HOSHI et al.

Group Art Unit: 1722

Application No.: 10/525,244

Examiner: G.N. RAO

Filed: February 22, 2005

Docket No.: 122810

For: SINGLE CRYSTAL, SINGLE CRYSTAL WAFER, EPITAXIAL WAFER, AND  
METHOD OF GROWING SINGLE CRYSTAL

**REQUEST FOR RECONSIDERATION AFTER FINAL REJECTION**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In reply to the June 21, 2007 Office Action, reconsideration of the rejections is respectfully requested in light of the following remarks.

Claims 13, 15, 17, 19 and 21-32 are pending in this application. In view of the foregoing, it is respectfully submitted that this application is in condition for allowance.

Favorable reconsideration and prompt allowance of all claims are earnestly solicited.